

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Takashi KANO et al.**

Serial Number: **Not Yet Assigned**

Filed: **August 30, 2001**

For: **METHOD OF FORMING NITRIDE-BASED SEMICONDUCTOR LAYER,
AND METHOD OF MANUFACTURING NITRIDE-BASED SEMICONDUCTOR
DEVICE**

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
Washington, D.C. 20231

August 30, 2001

Sir:

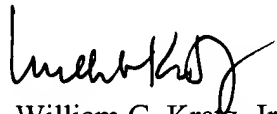
In compliance with 37 CFR 1.56, Applicants call to the attention of the Patent and Trademark Office the references listed on the attached PTO-1449.

A copy of each of the references is enclosed herewith.

In the event there are any fees due in connection with the filing of this paper, please charge

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Respectfully submitted,
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Enclosures: PTO-1449; References (5)

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